

*AF/IFW*  
PATENT  
Atty. Dkt. No. APPM/003177.D1/CPI/LB/PJS  
Serial No.: 10/646,405



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Wang, et al.

Serial No.: 10/646,405

Confirmation No.: 9508

Filed: 8/22/2003

For: Method and Apparatus For  
Ionized Plasma Deposition

§ Group Art Unit: 1753

§ Examiner: Rodney Glenn McDonald

MAIL STOP AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

CERTIFICATE OF MAILING  
37 CFR 1.8

I hereby certify that this correspondence is being deposited on  
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*Kenneth Zeh*  
Signature

**SECOND RESPONSE TO FINAL OFFICE ACTION DATED JANUARY 10, 2006**

In further response to the Final Office Action mailed January 10, 2006 and the Advisory Action dated March 28, 2006, having a shortened statutory period for response set to expire on April 10, 2006, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicant believes that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/APPM/003177.D1/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper. **Remarks** begin on page 7 of this paper.